ELEC 402

MOS Basics – part 2
Lecture 5

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MOS Current - Review

In general, the saturation region is entered when either the channel is pinched-off or the carriers achieved velocity saturation.

$$\text{if } V_{DS} \geq \frac{(V_{GS} - V_T)\, E_c L}{(V_{GS} - V_T) + E_c L} \Rightarrow \text{saturation}$$

$$\text{if } V_{DS} < \frac{(V_{GS} - V_T)\, E_c L}{(V_{GS} - V_T) + E_c L} \Rightarrow \text{linear}$$

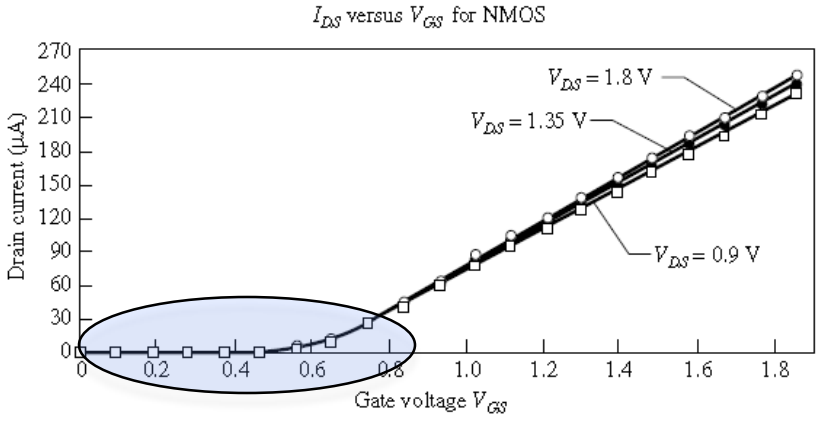
$$I_{DS} = W v_{sat} C_{ox} \frac{(V_{GS} - V_T)^2}{(V_{GS} - V_T) + E_c L} \quad \text{saturation}$$

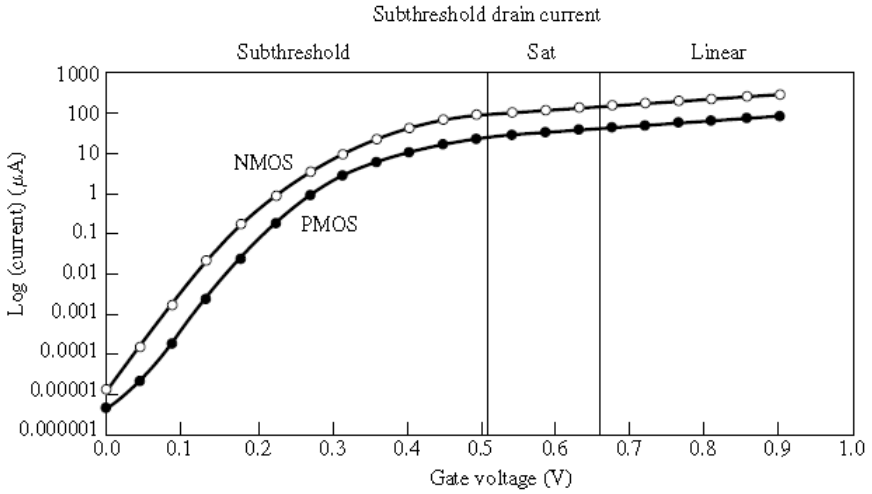
$$I_{DS} = \frac{W}{L} \cdot \frac{\mu_e C_{ox}}{\left(1 + \frac{V_{DS}}{E_c L}\right)} \left(V_{GS} - V_T - \frac{V_{DS}}{2}\right) V_{DS} \quad \text{linear}$$

Note that in extreme case ($E_cL >> V_{GS}, V_{DS}$) both equations translate to those of long channel devices

MOS Current - Sub threshold

Transistor turn-on/turn-off switching is a continuous process. At around V_{th} (and even below it) there is still significant leakage current.





$$I_{sub} = I_s e^{\frac{q(V_{GS} - V_T - V_{offset})}{nkT}} \left(1 - e^{\frac{-qV_{DS}}{kT}}\right)$$

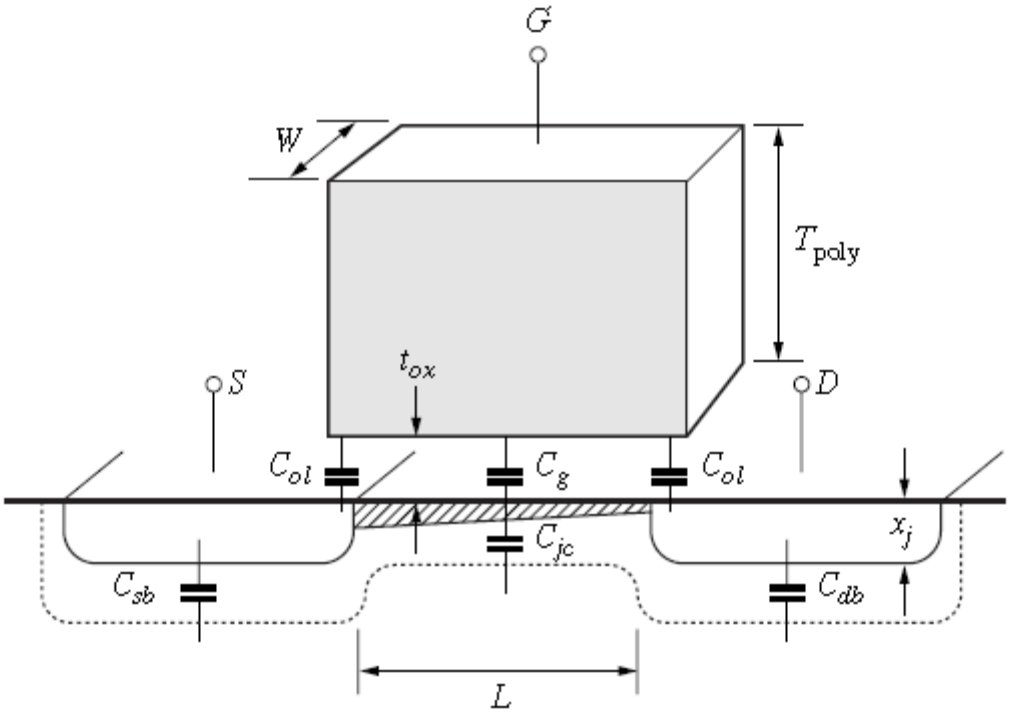
(Board Notes)

$$S = \Delta V_{GS} = \frac{nkT}{q} \ln(10)$$

slope factor

What is an ideal slope n and slope factor?

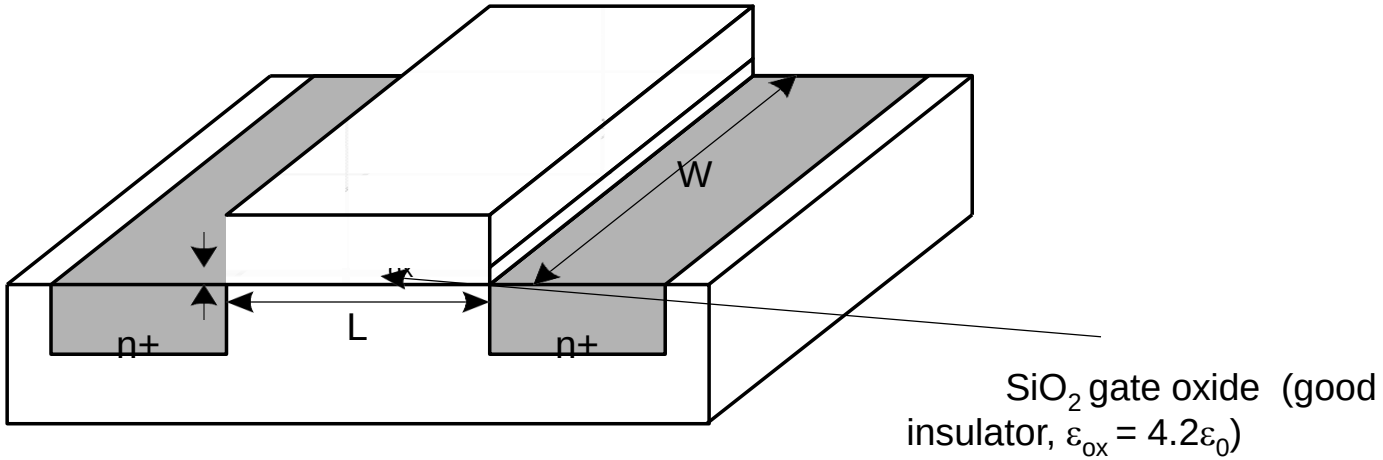
MOS Capacitances



- Each MOS device possess several junction and oxide capacitances (depends on dielectric and geometry) specified in units of fF/μm
- The charge/discharge of internal capacitances limits the switching speed

Gate Cap – Simple model

- $C_g = \varepsilon_{ox} WL/t_{ox} = C_{ox} WL = C_{permicron} W$
- $C_{permicron} = \varepsilon_{ox} L/t_{ox}$ should ~ remain unchanged with scaling
- Now typically about 1 fF/μm (~was 2 for older processes)

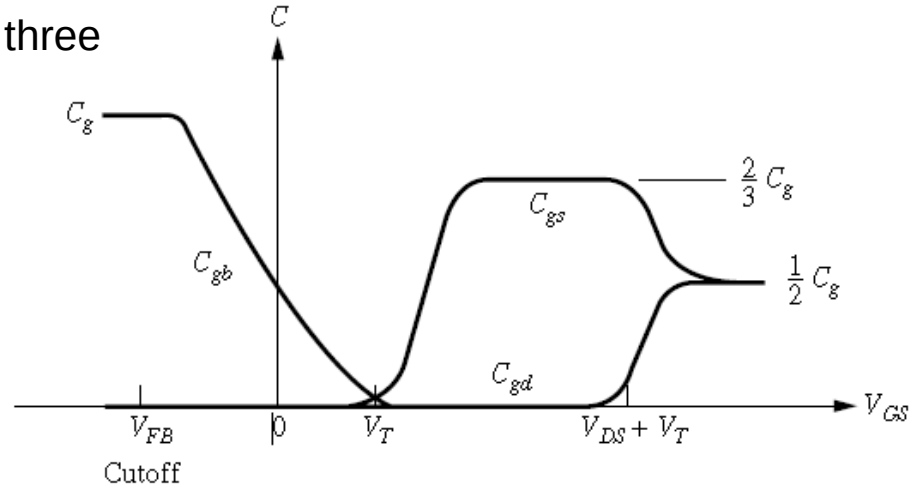


Gate Capacitance in different regions of operation

The total capacitace (Cg) is broken into three components C_{gb}, C_{gs} and C_{gd}

Why Does C_{gs} and C_{ds} change as we move from one region of operation to another?

- In cut-off there is no channel
- In linear region, $V_s \sim V_d$ V capacitance split between source and drain
- In saturation channel is pinched of on drain side $C_{gd} \sim 0$



	Cutoff	Linear	Saturation
C_{GS}	0	$\frac{1}{2}C_{ox}WL$	$\frac{2}{3}C_{ox}WL$
C_{GD}	0	$\frac{1}{2}C_{ox}WL$	0
C_{GB}	$C_{ox}WL$	0	0

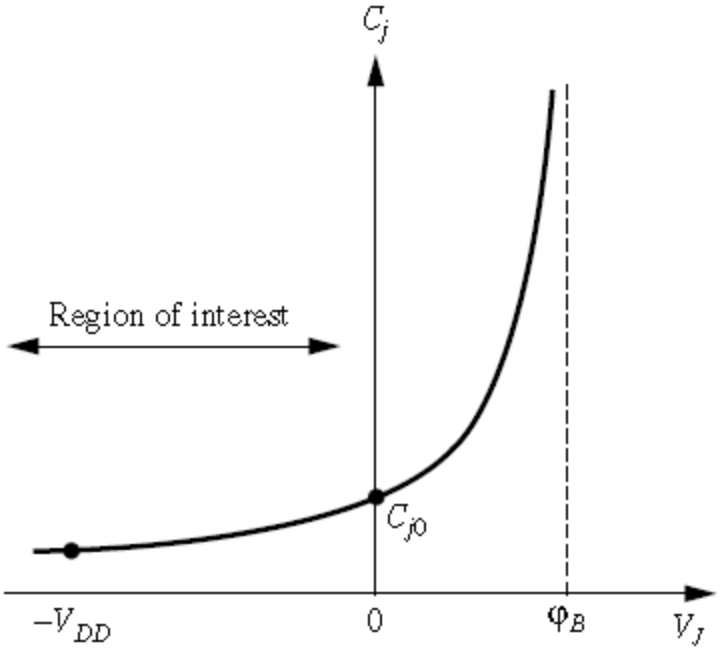
Junction Capacitance

A *pn* junction when forward biased shows the following I-V characteristics

$$I_D = I_S(e^{V_J/V_{th}} - 1)$$

A *pn* junction when reverse-biased has a leakage current and a wider depletion region resulting in a voltage-dependant junction capacitor

$$I_D = -I_S$$



Junction capacitance vs junction potentiai

$$C_J = \frac{C_{j0}\,A}{\left(1 - \frac{V_J}{\phi_B}\right)^m}$$

Capacitance of a *pn* junction

(in case of *abrupt* junction m=1/2)

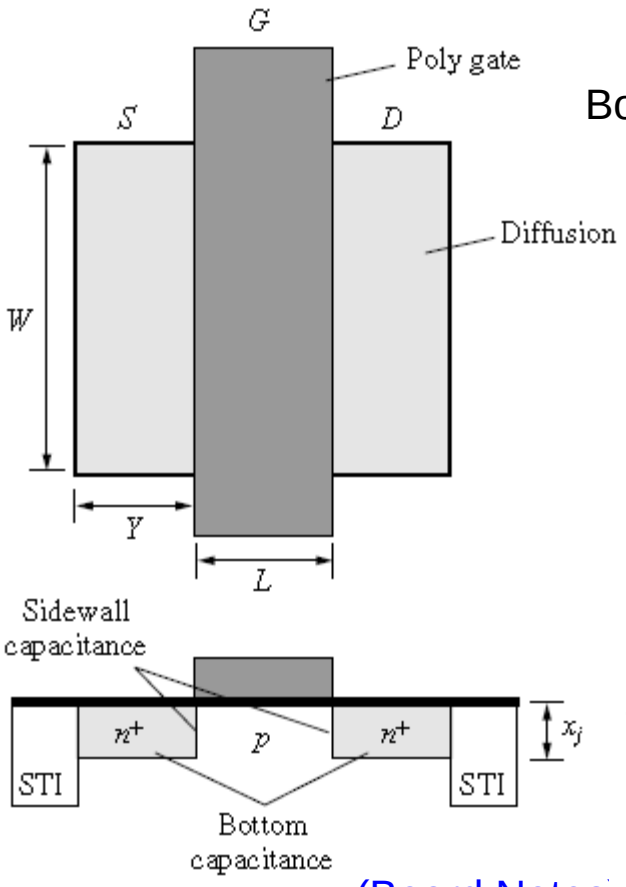
V_J is the voltage across Junction and C_{j0} is a process-Dependant constant

$$C_{j0} = \sqrt{\frac{\varepsilon_{si} q}{2\phi_B}\,\frac{N_A N_D}{N_A + N_D}}$$

Diode (junction) built-in potential

$$\phi_B = \frac{kT}{q}\ln\frac{N_A\,N_D}{n_i^2}$$

Junction Capacitance



$A_b = WY$

Bottom plate area

$A_{sw} = Wx_j$ Sidewall area

(for STI technology)

$$C_j = \frac{C_{jb}\,A_b}{\left(1 - \frac{V_J}{\phi_{Bb}}\right)^{mj}} + \frac{C_{jsw}\,A_{sw}}{\left(1 - \frac{V_J}{\phi_{Bsw}}\right)^{mjsw}}$$

If this is a voltage-dependant capacitance, how to model it as the device switches between different voltages?

1) Standard average (arithmetic mean)

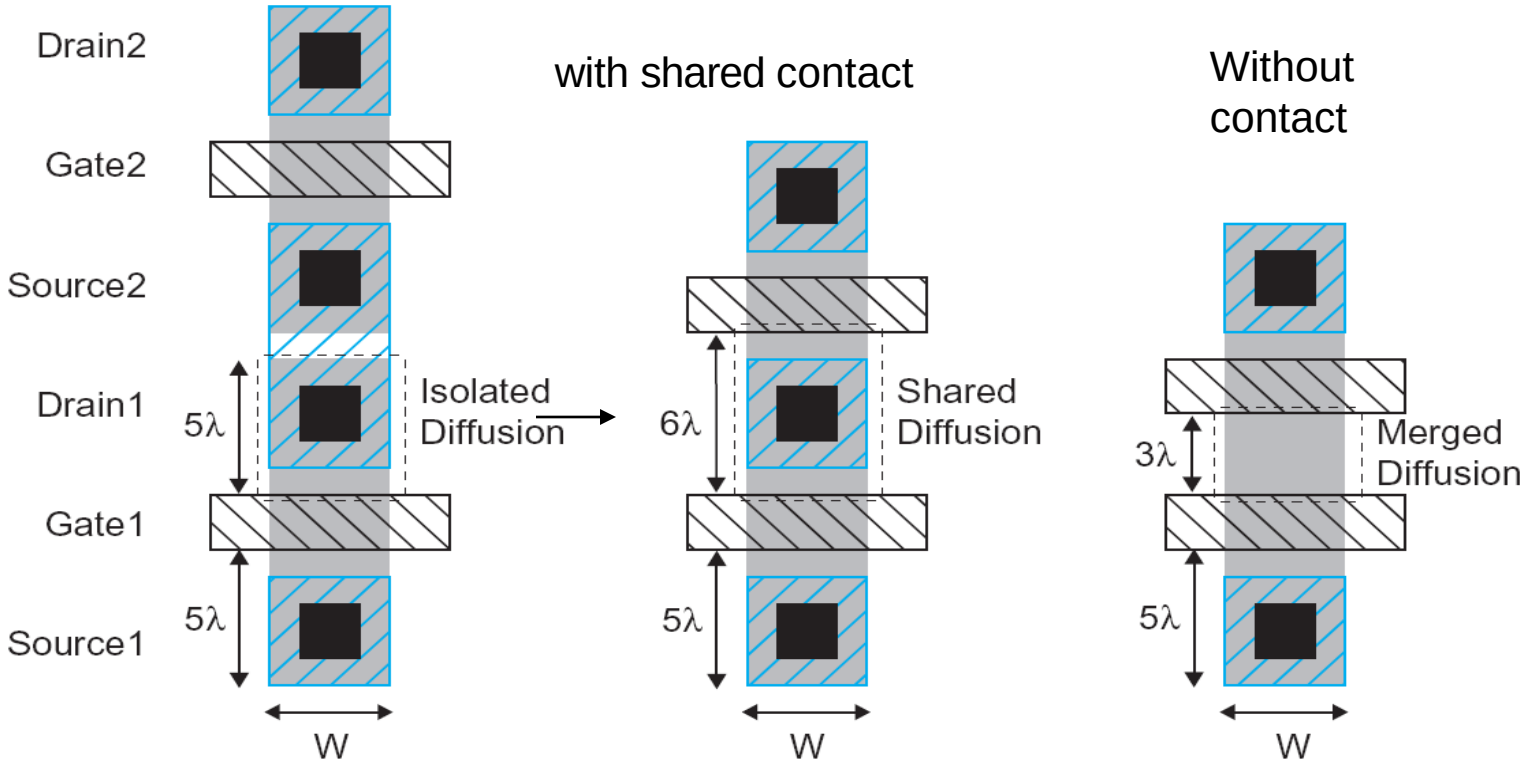
2) Calculate the effective capacitance from $C_{eff} = \Delta Q / \Delta V$

$$C_{eq} = -\frac{C_{jb}\phi_B}{(V_2 - V_1)(1 - m)}\left[\left(1 - \frac{V_2}{\phi_B}\right)^{1-m} - \left(1 - \frac{V_1}{\phi_B}\right)^{1-m}\right]$$

(Board Notes)

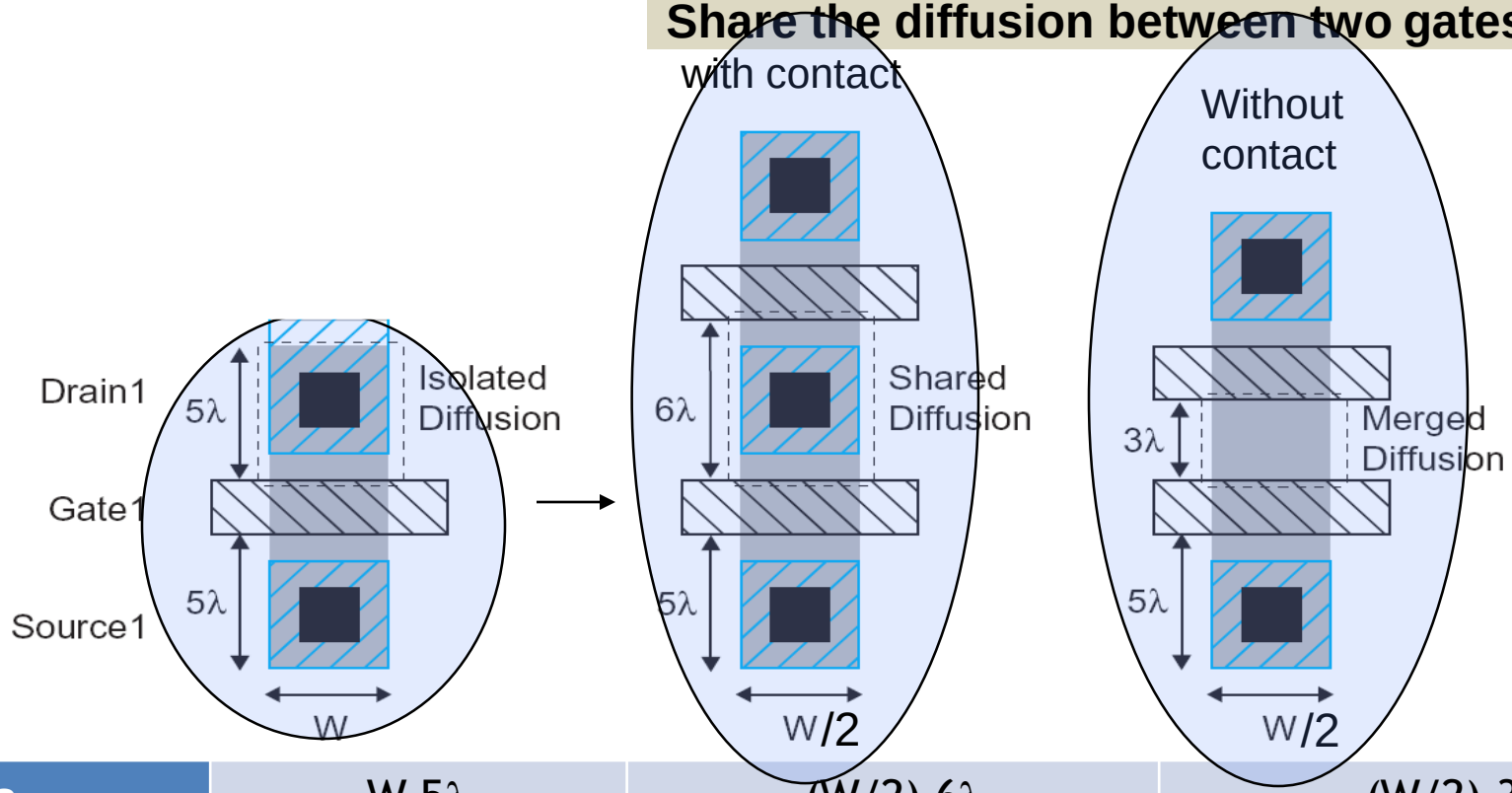
Layout – Two Transistor in series

Improved Layout



Layout - Minimize Area and Perimeter for a given W

Split the device into two,
Share the diffusion between two gates



Area	W.5λ	(W/2).6λ	(W/2).3λ
Perimeter	W	W	W

Junction Capacitance - Example

Junction Capacitance Calculations

Problem:

(a) Find ϕ_B and C_{jb} for an n^+p junction diode with $N_D = 10^{20}\,\text{cm}^{-3}$ and $N_A = (3)10^{17}\,\text{cm}^{-3}$.

Solution:

From Equation (2.37),

$$\phi_B = \frac{kT}{q} \ln \frac{N_A N_D}{n_i^2} = 0.026 \ln \left(\frac{3(10^{17})(10^{20})}{(1.45(10^{10}))^2} \right) = 1 \text{ V}$$

From Equation (2.39)

$$C_{jb} = \sqrt{\frac{\varepsilon_s q}{2\phi_B} \frac{N_A N_D}{N_A + N_D}} \approx \sqrt{\frac{\varepsilon_s q N_A}{2\phi_B}}$$

$$= \sqrt{\frac{11.7 * (8.85)(10^{-14}) * 1.6(10^{-19})(3)(10^{17})}{2(1.0)}} \approx 1.6 \frac{\text{fF}}{\mu\text{m}^2}$$

Junction Capacitance – Example cont'd

Problem:

(b) For a 0.13 μm process, $W = 400$ nm, $L = 100$ nm, $x_j = 50$ nm, and the diffusion extension is $Y = 300$ nm. Using the layout of Figure 2.20, find C_J in units of fF for and $V_J = 0$ and $V_J = -1.2$ V.

Solution:

For $V_J = 0$, the value is obtained by multiplying C_{jb} with $(Y+x_j)W$

$$C_J = C_{jb}(Y + x_j)W = 1.6\,\text{fF}/\mu\text{m}^2 \times (0.3\,\mu\text{m} + 0.05\,\mu\text{m}) \times 0.4\,\mu\text{m} \approx 0.22\,\text{fF}$$

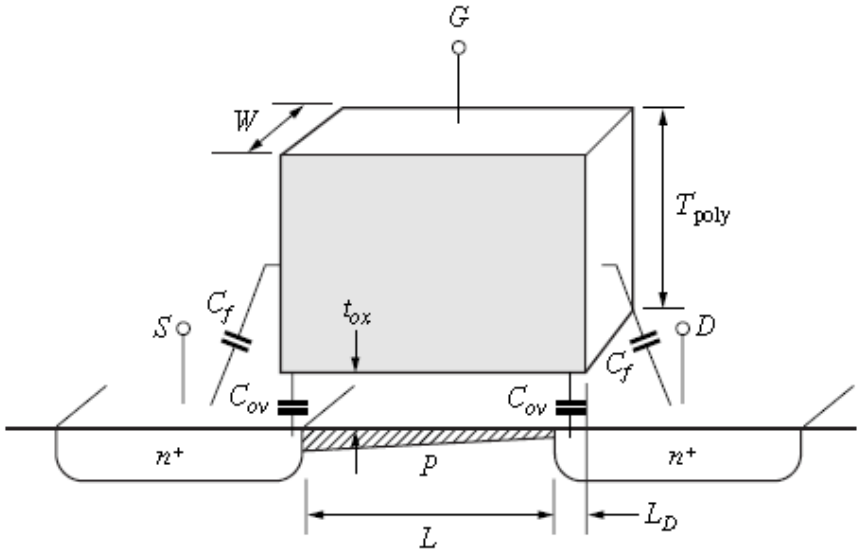
For $V_J = -1.2$,

$$C_J = \frac{C_{jb}(Y + x_j)W}{(1 - V_J/\phi_B)^m}$$

$$= \frac{1.6\ \text{fF}/\mu\text{m} \times (0.3\ \mu\text{m} + 0.05\ \mu\text{m}) \times 0.4\ \mu\text{m}}{(1 + 1.2/1.0)^{1/2}} = 0.16\ \text{fF}$$

Exercise: Use the integral (effective capacitance technique) and compare against the average here

Overlap Capacitance



-The lateral diffusion creates an overlap between gate and drain (source areas) creating a parasitic capacitance called *overlap* capacitance

- The proximity of drain (source) regions to the sidewall of gate in DSM contact creates another parasitic cap called *fringe* capacitance

$$C_f = \frac{2\varepsilon_{ox}}{\pi} \ln\left(1 + \frac{T_{poly}}{t_{ox}}\right)$$

Per unit width capacitance $C_{ol} = C_{ov} + C_f$

$$C_{ov} = C_{ox} \times L_D$$

Summary

- The current capability ratio of NMOS and PMOS decreases (due to velocity saturation) as we move further into short channel regime.
- There is an exponential dependence of leakage current on V_{GS} in sub threshold region.
- A MOS device has three main physical types of capacitance
- The gate-oxide capacitance is re-distributed between source and drain, i.e. C_{GS} and C_{DS} vary, as device moves from linear to saturation region.
- The junction capacitance is voltage-dependant; we need to find an effective (average) capacitance for switching devices.
- The overlap/fringe capacitance becomes more important in DSM technologies.